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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named
Inventor : Benjamin Y.H. Liu et al.

Appln. No. : 10/769,011

Filed : January 30, 2004

For : HIGH-PERFORMANCE AND MULTI-
LIQUID-PRECURSOR
VAPORIZATION IN
SEMICONDUCTOR THIN FILM
DEPOSITION

Docket No.: M419.12-0043

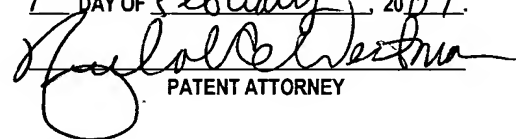
Group Art Unit: 1763

Examiner:

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I HEREBY CERTIFY THAT THIS PAPER IS BEING
SENT BY U.S. MAIL, FIRST CLASS, TO THE
COMMISSIONER FOR PATENTS, P.O. BOX 1450,
ALEXANDRIA, VA 22313-1450, THIS

7th DAY OF February, 2007.

PATENT ATTORNEY

Sir:

In response to the Official Action Mailed January 11, 2007,
it is respectfully requested that the following amendments be made.